

Appl. No. 09/675,220  
Amendment dated:  
Reply to OA of: May 6, 2004

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Minoru NAKANO et al. Confirmation No.: 1221  
Appl. No. : 09/675,220  
Filed : September 29, 2000  
Title : METHOD AND APPARATUS FOR CONTROLLING A  
SEMICONDUCTOR FABRICATION TEMPERATURE  
  
TC/A.U. : 2825  
Examiner : Caridad M. Everhart  
  
Docket No. : 3094/FLK (032878-87728)

**AMENDMENT**

Commissioner  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in response to the Official Action of May 6, 2004, in connection with the  
above-identified application.

Please amend the application as follows:

**Amendments to the claims** are reflected in the listing of claims which begins  
on page 2 of this paper

**Remarks** begin on page 6 of this paper.

**CERTIFICATION OF FACSIMILE TRANSMISSION**  
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